



N-type Silicon Carbide Substrate Specification

Sunup SiC ver.230929

Sunup ID	S6P-001	S6D-001	S6M-001
Grade	Prime Grade	Dummy Grade	Mechanical grade
Poly type	4H	4H	4H
Diameter	150 mm \pm 0.25 mm	150 mm \pm 0.25 mm	150 mm \pm 0.25 mm
Surface Orientation Off-axis	4.0 ° toward <11-20> \pm 0.5°	4.0 ° toward <11-20> \pm 0.5°	4.0 ° toward <11-20> \pm 0.5°
Primary Flat Orientation	<1-100> \pm 5.0°	<1-100> \pm 5.0°	<1-100> \pm 5.0°
Primary Flat Length	47.5 mm \pm 2.0 mm	47.5 mm \pm 2.0 mm	47.5 mm \pm 2.0 mm
TTV	\leq 10 μ m	\leq 15 μ m	\leq 15 μ m
LTV (10*10mm,Max)	\leq 5 μ m	\leq 5 μ m	N/A
BOW (ablolute value)	\leq 30 μ m	\leq 35 μ m	\leq 45 μ m
WARP	\leq 40 μ m	\leq 40 μ m	\leq 65 μ m
TED	3000 ea/cm ²	N/A	N/A
BPD	1500 ea/cm ²	N/A	N/A
TSD	400 ea/cm ²	N/A	N/A
Wafer Edge	Chamfer	Chamfer	Chamfer
Micropipe Density	\leq 1 micropipes/cm ²	\leq 10 micropipes/cm ²	N/A
Polytype areas by high-intensity light	None permitted	\leq 10 % area	N/A
Resistivity	0.015 Ω ·cm ~ 0.025 Ω ·cm	0.015 Ω ·cm ~ 0.028 Ω ·cm	\leq 0.040 Ω ·cm
Thickness	350 μ m \pm 25.0 μ m	350 μ m \pm 25.0 μ m	350 μ m \pm 25.0 μ m
Surface finish	Double Side Polish	Double Side Polish	Double Side Polish
Surface Roughness	CMP Si Face Ra \leq 0.5 nm	CMP Si Face Ra \leq 0.5 nm	N/A
Scratch (by CS8520)	Total length \leq 75 mm	Total length \leq 150 mm	N/A
Cracks by high-intensity light	None Permitted	None Permitted	None Permitted
Edge Chip /indents by diffuse lighting	None permitted	Qty2<1.0mm width and depth	N/A
Edge Exclusion	3mm	3mm	3mm